

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Tre application of: NAKAYAMA et al.

**Application No.** 09/828,301

Filed: April 6, 2001

Confirmation No. 6580

For: APF

APPARATUS AND METHODS FOR

MEASURING SURFACE PROFILES AND

WAVEFRONT ABERRATIONS, AND LENS SYSTEMS COMPRISING SAME

Examiner: Kevin K. Pyo

Art Unit: 2878

Attorney Reference No. 4641-58305

CERTIFICATE OF MAILING

I hereby certify that this paper and the documents referred to as being attached or enclosed herewith are being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA 22313-1450 on the date shown below.

Attorney for Applicant(s)

Date Mailed October 3, 2003

COMMISSIONER FOR PATENTS P.O. BOX 1450 ALEXANDRIA, VA 22313-1450

## AMENDMENT AND REPLY TO OFFICE ACTION

This responds to the Office action dated May 8, 2003. Please amend the referenced application as follows:

Amendments to the Specification begin on page 2.

Amendments to the Claims are reflected in the listing of claims, which begins on page 3.

Remarks begin on page 13.

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